

# WxZ RPS Data Sheet

- Remove AIF formation from RF cleaning process – Remove RF hardware.
- If uWave unit, replace with reliable Astron & increase removal rate.
- Extend MWBC:
  - Installed base is demonstrating > 60K WBWC  
No Change in Edge Exclusion, no AIFx build up on heater/CPR.
- No Ar Backside Pressure/WOP
- No change to Nucleation resistivity with VAT valve option @ 90 or 300torr
- Heater Lifetime >300K Wafers
- Lids: Standard, ECL, Sprint (uWave)
- >140 units in production
- Complete BKM manual with installation, schematics and Process Recipe BKM's.
  - 85KA removal (4KA dep=every 20 wafers)

